

Abstract

An object of the present invention is to provide an apparatus for removing particles which effectively eliminates particles in the vacuum container unit without
5 degrading the rate of operation of the processing device, and is simple and inexpensive to embody.

The apparatus for removing particles in accordance with the present invention is for a processing device including a vacuum container unit having a plurality of
10 chambers in which a predetermined process is performed on a wafer carried in by a conveyer unit in atmosphere. The apparatus comprises a charge neutralizing means for neutralizing charges generated on a surface of the wafer, the charge neutralizing means being mounted in a waiting-
15 accommodation unit which constitutes a part of the conveyer unit, and a charging means for adsorbing particles in the vacuum container unit by electrostatic force, the charging means being mounted in the vacuum container unit.